



Docket No.: 294256US26PCT



COMMISSIONER FOR PATENTS  
ALEXANDRIA, VIRGINIA 22313

ATTORNEYS AT LAW

STEVEN P. WEIHROUCH  
(703) 413-3000  
SWEIHROUCH@OBLON.COM

RE: Application Serial No.: 10/587,394

Applicants: Shuichi ISHIZUKA, et al.

Filing Date: July 27, 2006

For: METHOD FOR CLEANING PROCESS CHAMBER OF  
SUBSTRATE PROCESSING APPARATUS, SUBSTRATE  
PROCESSING APPARATUS, AND METHOD FOR PROCESSING  
SUBSTRATE

Group Art Unit: 1792

Examiner: MILLER, JR, J. A.

SIR:

Attached hereto for filing are the following papers:

**Response to Restriction Requirement**

Credit card payment is being made online (if electronically filed), or is attached hereto (if paper filed), in the amount of **\$0.00** to cover any required fees. In the event any variance exists between the amount enclosed and the Patent Office charges for filing the above-noted documents, including any fees required under 37 C.F.R. 1.136 for any necessary Extension of Time to make the filing of the attached documents timely, please charge or credit the difference to our Deposit Account No. **15-0030**. Further, if these papers are not considered timely filed, then a petition is hereby made under 37 C.F.R. 1.136 for the necessary extension of time.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,  
MAIER & NEUSTADT, P.C.



Steven P. Weihrouch

Registration No. 32,829

Customer Number

**22850**

(703) 413-3000 (phone)  
(703) 413-2220 (fax)  
(OSMMN 10/08)